

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#10/Electon

In re Patent Application: Becky Losee

Serial No.: 09/843,023

Filed: April 26, 2001

For: METHODS FOR ETCHING SILICON

TRENCHES

Confirmation No. 7229

Group Art Unit: 2823

Examiner: J. Maldonado

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Commissioner for Patents Washington, D.C. 20231

Box Non-Final Response

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In response to the Office Action dated August 21, 2002Applicant requests reconsideration of the restriction requirement and examination of all claims in light of the following remarks.

Remarks

The Office required restriction to one of the following groups of inventions under 35 U.S.C. § 121:

Group I: claims 1-24, drawn to a method of manufacturing a semiconductor device, classified in class 438, subclass 709; and

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D. C. 20231, on this 20th day of September 2002.

Signed:

Dated: 9

9/20/2002